

**10/566750**

OGOSH45USA

AP20 Rec'd 01 FEB 2006 01 FEB 2006  
IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of: )  
 ) Examiner:  
 Yuichiro Shindo et al. )  
 ) Group Art Unit:  
 Application No.: )  
 )  
 Corresponding International Filing No.: )  
 PCT/JP2004/010714 )  
 )  
 Filed: Herewith )  
 )  
 For: HIGH PURITY COPPER )  
 SULFATE AND METHOD FOR )  
 PRODUCTION THEREOF )

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Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

**FIRST PRELIMINARY AMENDMENT**

Sir:

**Before calculating the filing fee**, please amend the above-identified patent application as follows.

**Amendments to the Claims** are reflected in the listing of claims which begins on page two of this paper.

**Remarks** begin on page three of this paper.